

Session:

Millimeter-Wave PAs for 5G and Beyond

Large-Signal Performance of AlInN/GaN-on-Silicon HEMTs at 94 GHz

C.R. Bolognesi

*Millimeter-Wave Electronics Group (MWE)
ETH-Zürich, Gloriastrasse 35, Zürich 8092, Switzerland
<http://www.mwe.ee.ethz.ch/>*

Collaborators

■ ETHZ

- S. Tirelli
- D. Marti
- Dr. V. Teppati

■ EPFL

- L. Lugani
- M. Malinverni
- J.-F. Carlin
- E. Feltin
- M.A. Py
- Prof. N. Grandjean



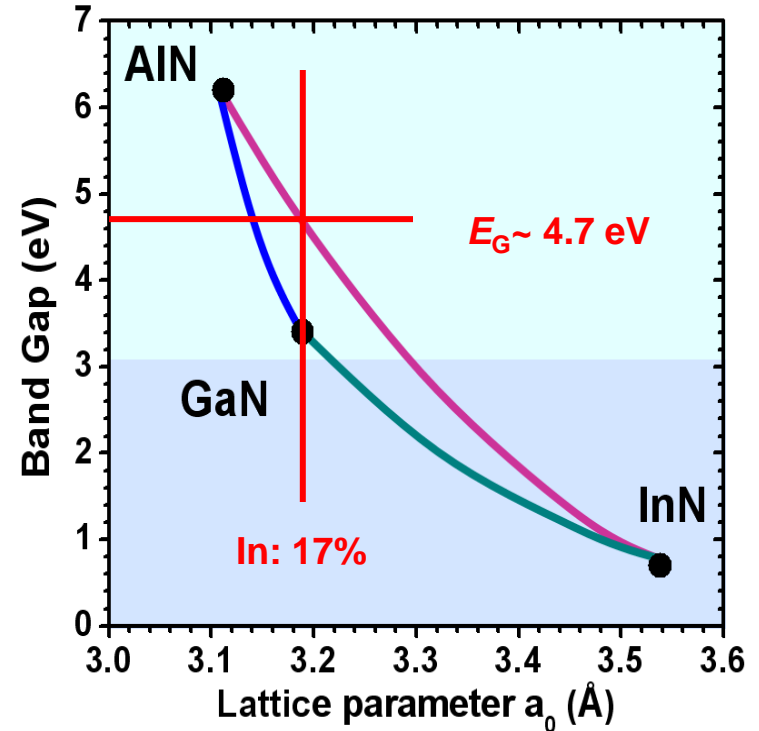
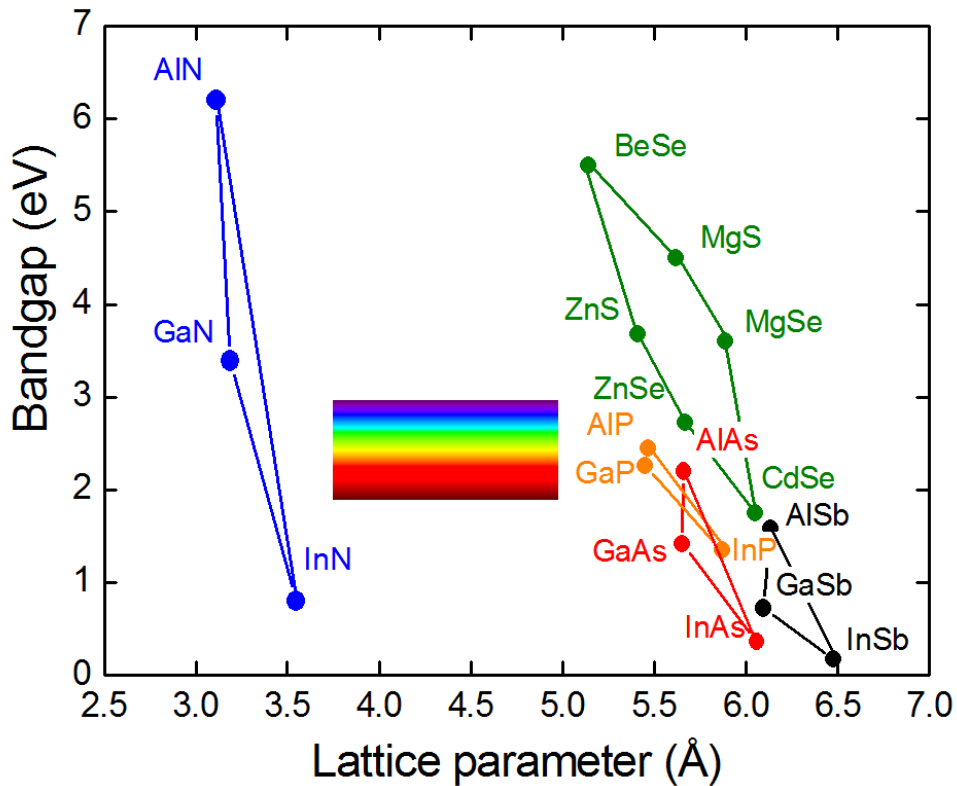
ÉCOLE POLYTECHNIQUE
FÉDÉRALE DE LAUSANNE

Considerations / Outline

- **AlInN/GaN Materials**
 - Lattice-Matching to GaN
 - Reduced Surface Depletion *vs.* AlGaN/GaN

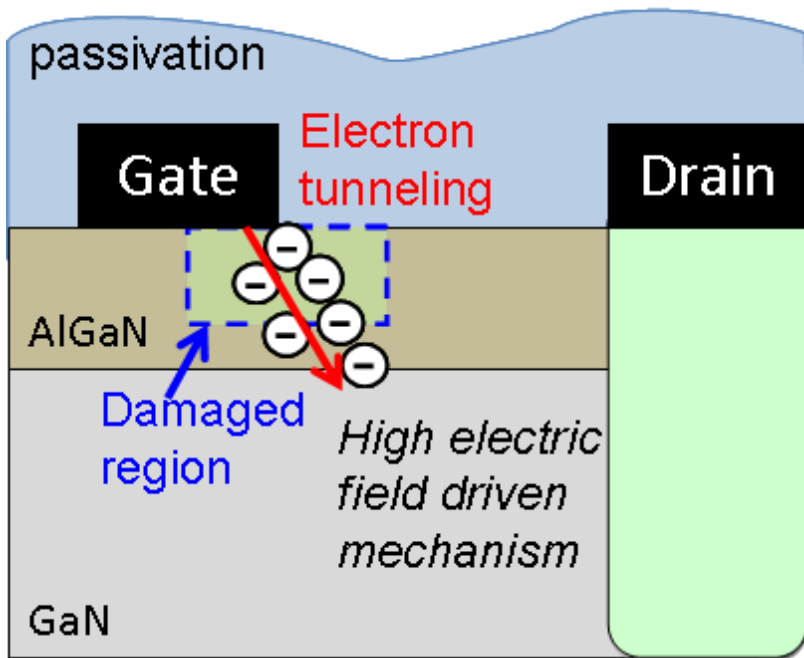
- **Requirements for mm-Wave HEMTs**
 - Gate-Channel Spacing / Source-Drain Separation
 - Short-Channel Effects (SCEs)
 - Series Resistances / Ohmic Contacts (Annealed *vs.* Regrown)
 - Large-Signal on Silicon (W-Band)
 - PDK and W-Band Prototype on Silicon

Lattice Matching ($\text{Al}_{0.83}\text{In}_{0.17}\text{N}:\text{GaN}$)

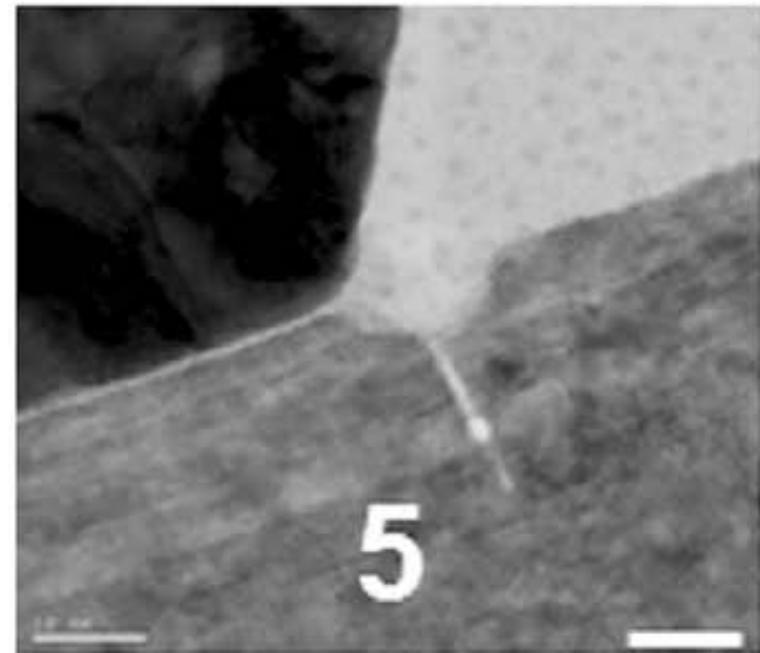


Materials

Lattice Matching: A Reliability Enhancer (?)



G. Meneghesso et al.



Park et al. (TRIQUINT)

Cumulative Strain (Mismatch + Piezo) Correlated to Device Degradation

Materials

AllnN/GaN High Temperature Stability (1000°C)



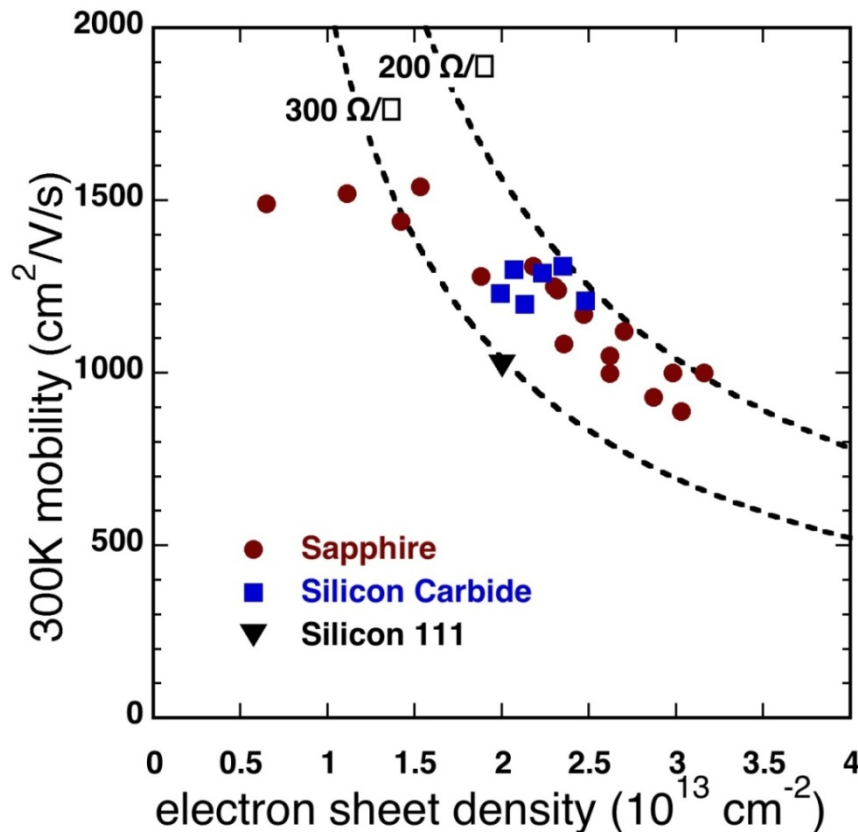
F. Medjdoub *et al.*, IEDM 2006

AllnN/GaN HEMTs Survive 1000°C
Temperatures

(Potential for High-T Electronics)

Materials

Substrate Choices



Silicon:

1,030 cm^2/Vs @ $2 \times 10^{13} / \text{cm}^2$
 300 Ω/\square (-17% mismatch)

SiC:

1,300 cm^2/Vs @ $2.4 \times 10^{13} / \text{cm}^2$
 205 Ω/\square (-3.5% mismatch)

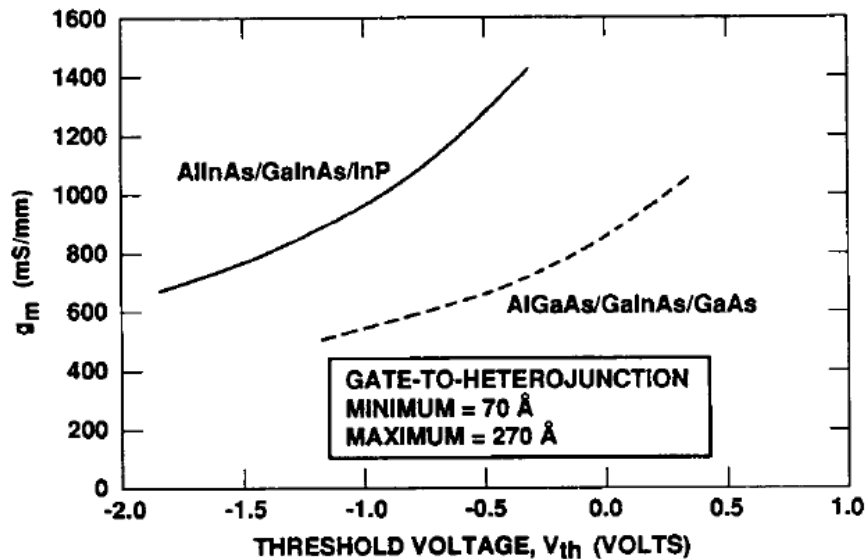
Excellent Mobility in 2DEG:

Dislocations are screened by the high carrier density

Appl. Phys. Lett. **89**, 062106 (2006)

Materials

Surface Depletion: InP vs. GaAs HEMT Analogy



Ultra-High-Speed Modulation-Doped Field-Effect Transistors: A Tutorial Review

LOI D. NGUYEN, MEMBER, IEEE, LAWRENCE E. LARSON, SENIOR MEMBER, IEEE, AND UMESH K. MISHRA, SENIOR MEMBER, IEEE

Proc. IEEE, p.494 (1992)

Reduced Gate-to-Channel Distance

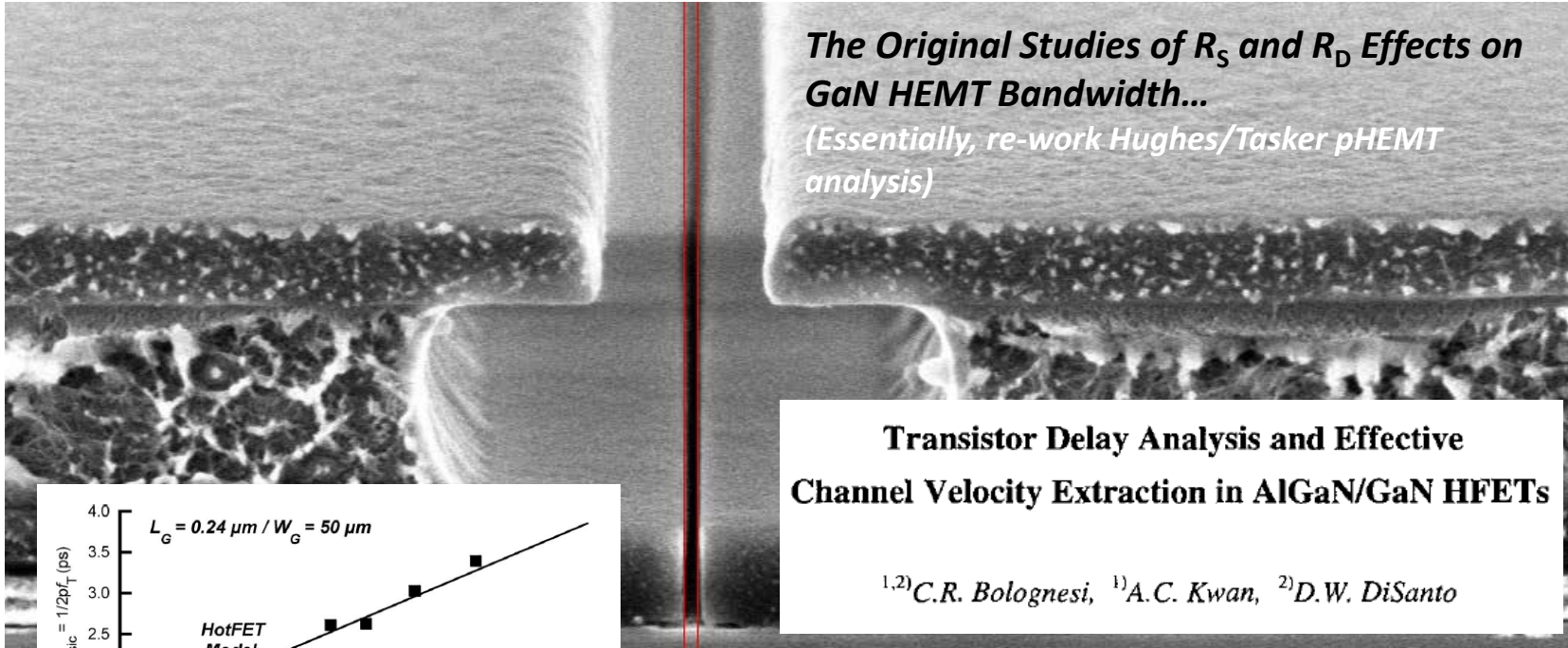
Theoretical Advantages:

- Higher G_M
- Higher Current Drive, $I_{D\text{MAX}}$
- Improved Aspect Ratio L_G/d
- Weaker Short-Channel Effects
- Textbook Approach to High-Speed

All Recent Record GaN HEMTs:

- Thin Barriers (AlInN or AlN)
- Higher Channel Sheet Density

Requirements: Reduced S/D Spacing



*The Original Studies of R_S and R_D Effects on GaN HEMT Bandwidth...
(Essentially, re-work Hughes/Tasker pHEMT analysis)*

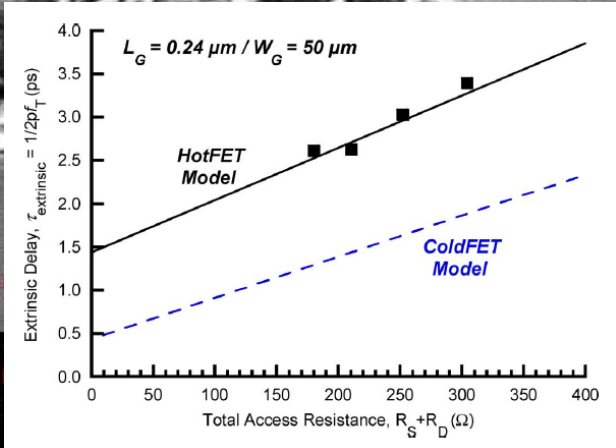
Transistor Delay Analysis and Effective Channel Velocity Extraction in AlGaIn/GaN HFETs

^{1,2}C.R. Bolognesi, ¹A.C. Kwan, ²D.W. DiSanto

2914 IEEE TRANSACTIONS ON ELECTRON DEVICES, VOL. 53, NO. 12, DECEMBER 2006

At-Bias Extraction of Access Parasitic Resistances in AlGaIn/GaN HEMTs: Impact on Device Linearity and Channel Electron Velocity

David W. DiSanto, Member, IEEE, and C. R. Bolognesi, Senior Member, IEEE



$L_G = 0.24 \mu\text{m} / W_G = 50 \mu\text{m}$

Extrinsic Delay, $\tau_{\text{extrinsic}} = 1/2p\tau_T$ (ps)

HotFET Model

ColdFET Model

Total Access Resistance, $R_S + R_D$ (Ω)

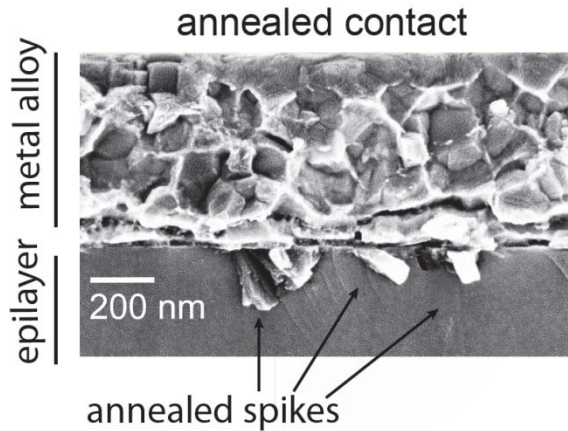
Total Access Resistance, $R_S + R_D$ (Ω)	Extrinsic Delay, $\tau_{\text{extrinsic}}$ (ps)
0	~1.4
~180	~2.6
~210	~2.6
~250	~3.0
~300	~3.4

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 - Large-Signal on Silicon (94 GHz)

Ohmic Contacts (1)



Metallization:

Ti / Al / Mo / Au

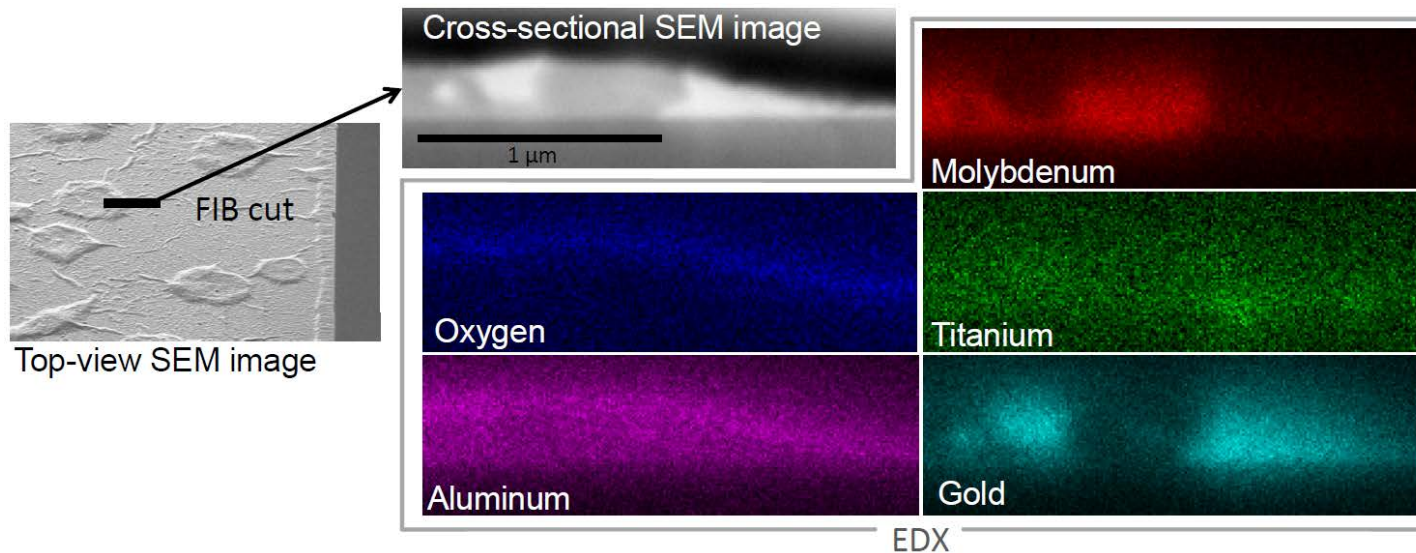
Yields

$R_C \approx 0.3$ to $1 \Omega \cdot \text{mm}$
(strong variability)

Requirements:

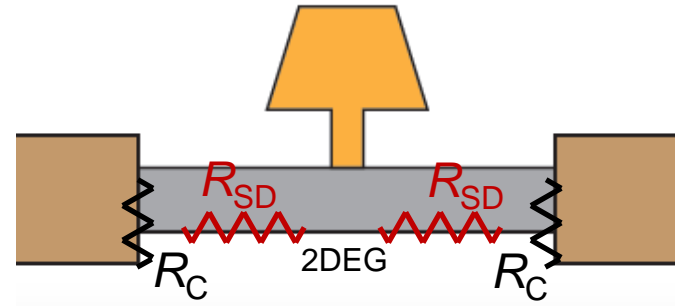
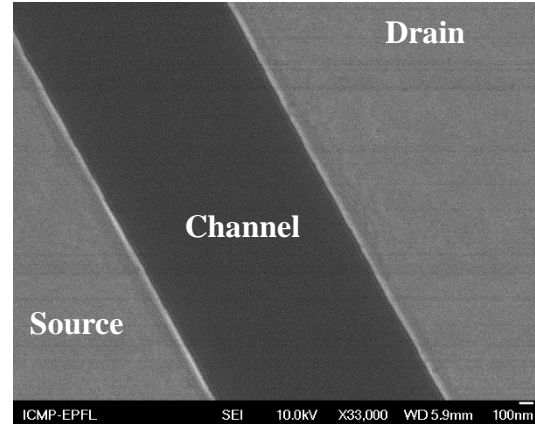
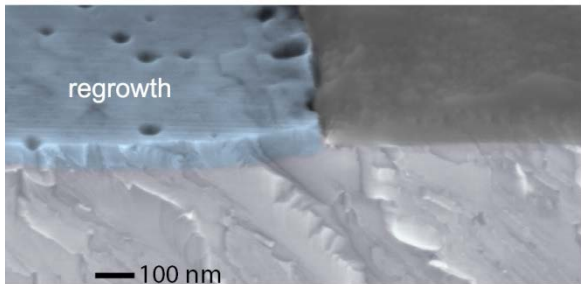
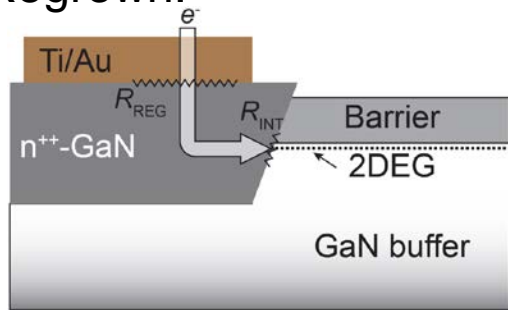
- Good Morphology
- Low Contact Resistance

Rapid Thermal Annealing
 $T \sim 850^\circ\text{C}$



Regrown Contacts (2)

Regrown:

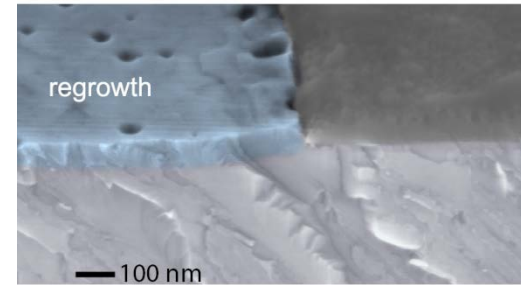
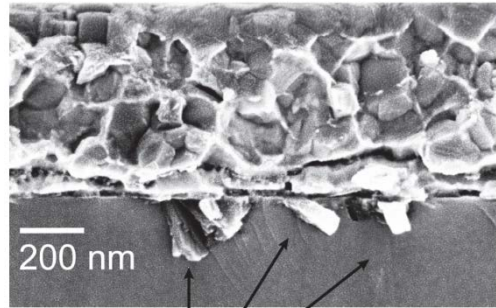


Beneficial for Short L_{SD} Spacings ($R_{SD} < R_C$)

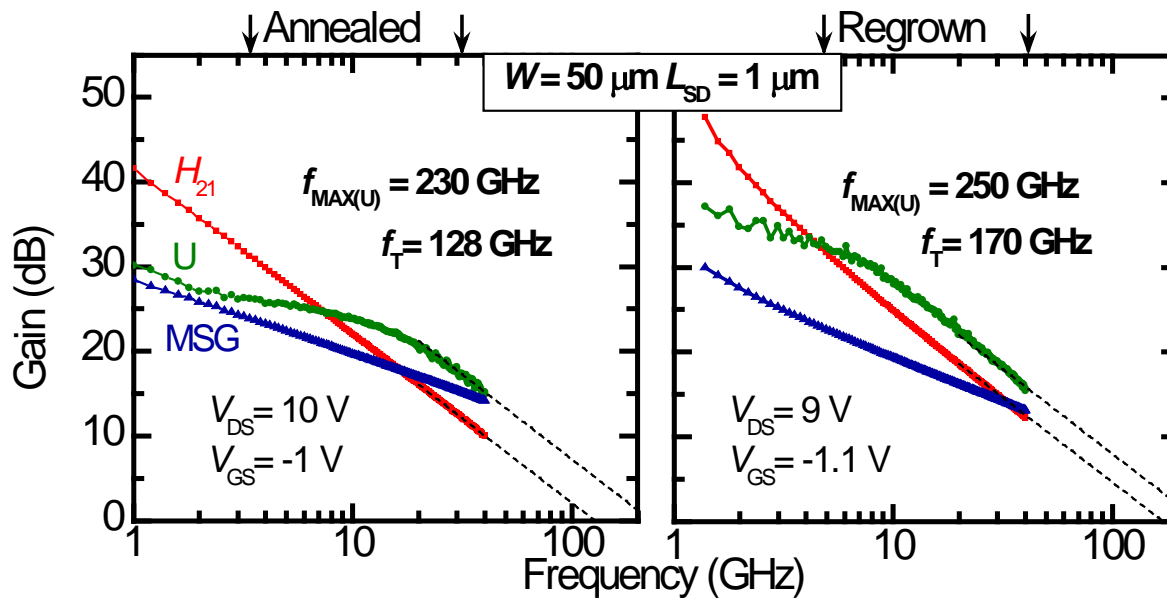
Better Reproducibility with Respect to Annealed Ohmics

(Best Example: Shinohara *et al.*, *HRL*)

Regrown Contacts (3)



annealed spikes

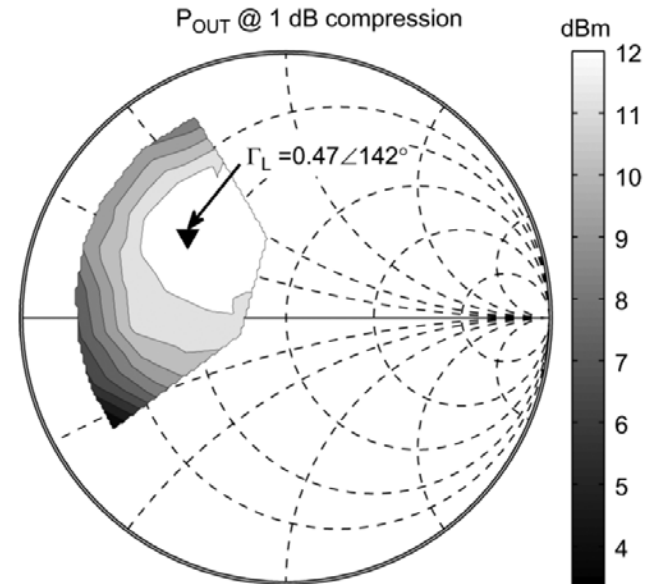
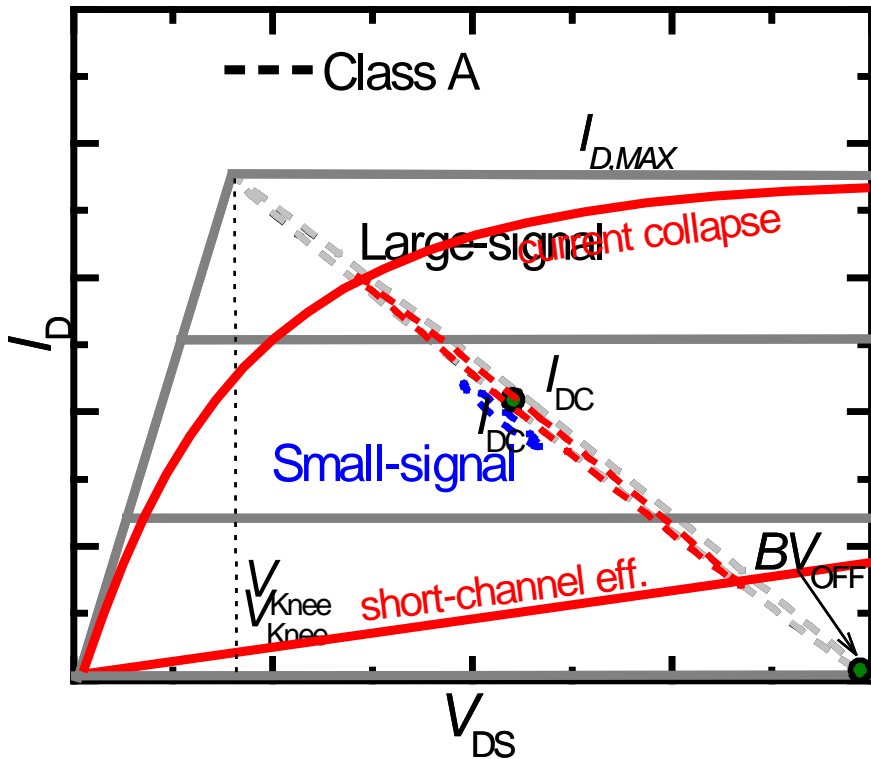
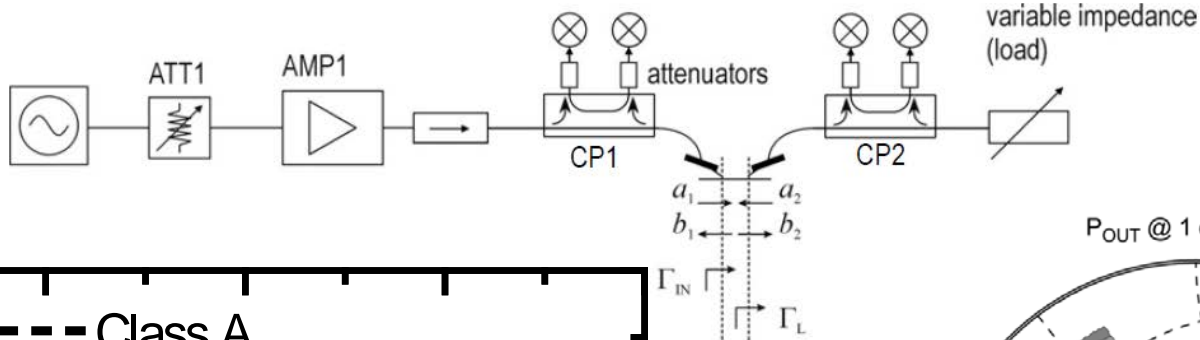


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 - **Large-Signal on Silicon (94 GHz / W-Band)**

Large-Signal Operation

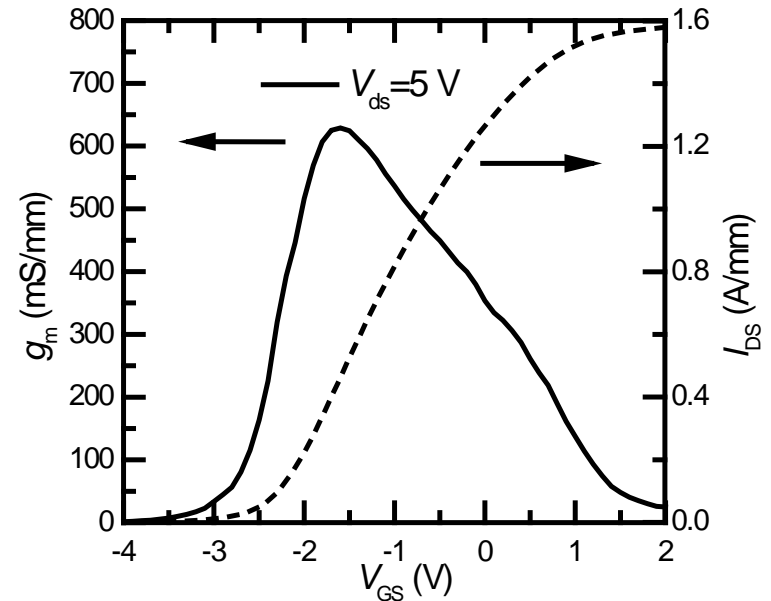
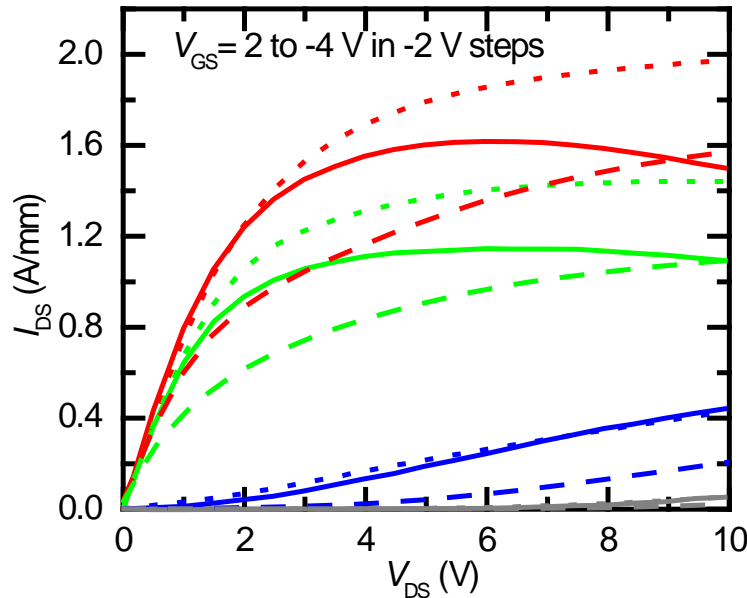


- + Output Impedance Matched for max P_{OUT}
- + Current Collapse and SCEs Limit P_{OUT}

Large-Signal Operation (On Silicon)

$d = 7.5 \text{ nm}$, $L_G = 50 \text{ nm}$, $L_{SD} = 2 \text{ }\mu\text{m}$ on HR-Silicon.

Improved Buffer / Channel Design. Regrown Contacts.



DC Characteristics

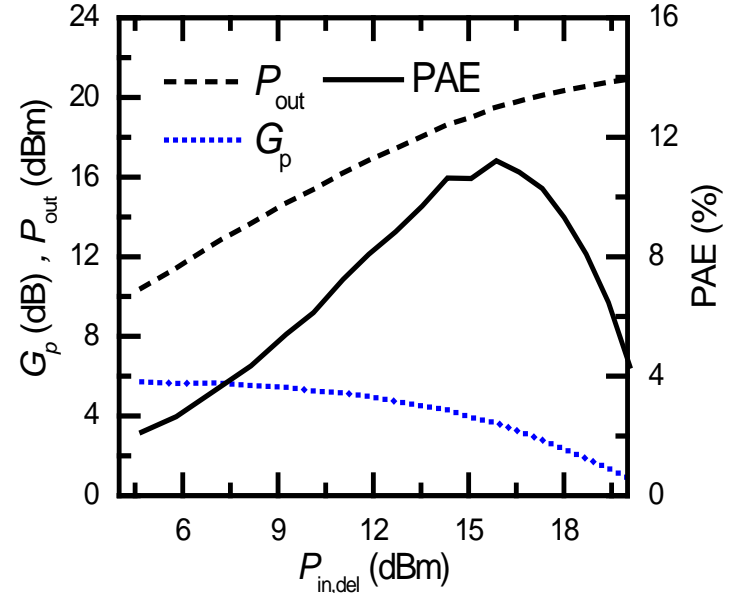
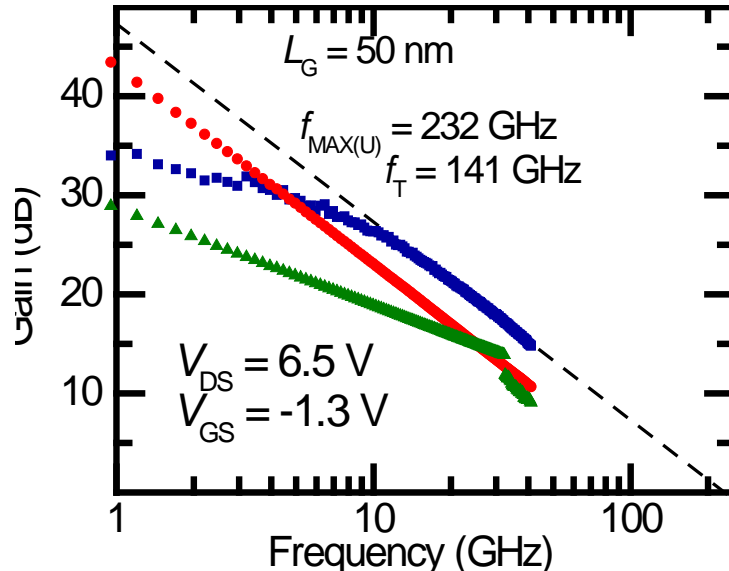
- + $G_M > 650 \text{ mS/mm}$
- + Adequate Pinch-Off
- + Good Transport: $\mu = 1200 \text{ cm}^2/\text{Vs}$ ($300 \text{ }\Omega/\text{sq}$)
- + Back-Barrier not Implemented

Large-Signal Operation

$d = 7.5 \text{ nm}$, $L_G = 50 \text{ nm}$, $L_{SD} = 2 \text{ }\mu\text{m}$ on HR-Silicon.

Improved Back-Buffer / Channel Design. Regrown Contacts

Power gain (G_p), output power (P_{out}), power added efficiency (PAE) at $V_{GS} = -1.2 \text{ V}$ and $V_{DS} = 9 \text{ V}$ at 94 GHz for a 50 nm gate length device, with source-drain spacing of 2 μm , source-gate spacing 0.5 μm and a total gate width of 100 μm



94 GHz Initial Results

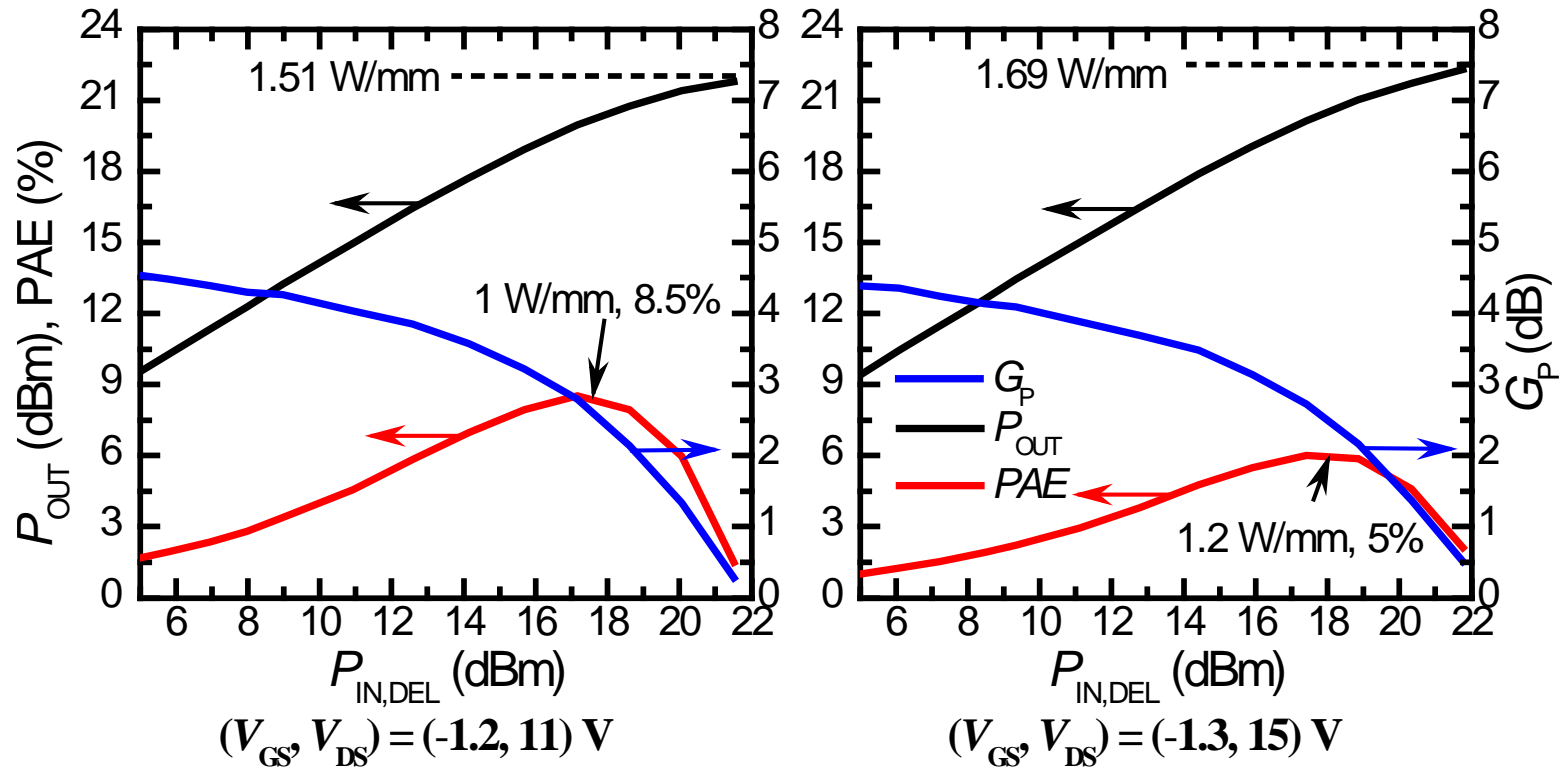
1 W/mm / PAE = 12% / $G_p = 4 \text{ dB}$ @ $P_{IN,Del} = 16 \text{ dBm}$
(Better than 1 W/mm Result on SiC)

Large-Signal Operation

@ 94 GHz on SiC

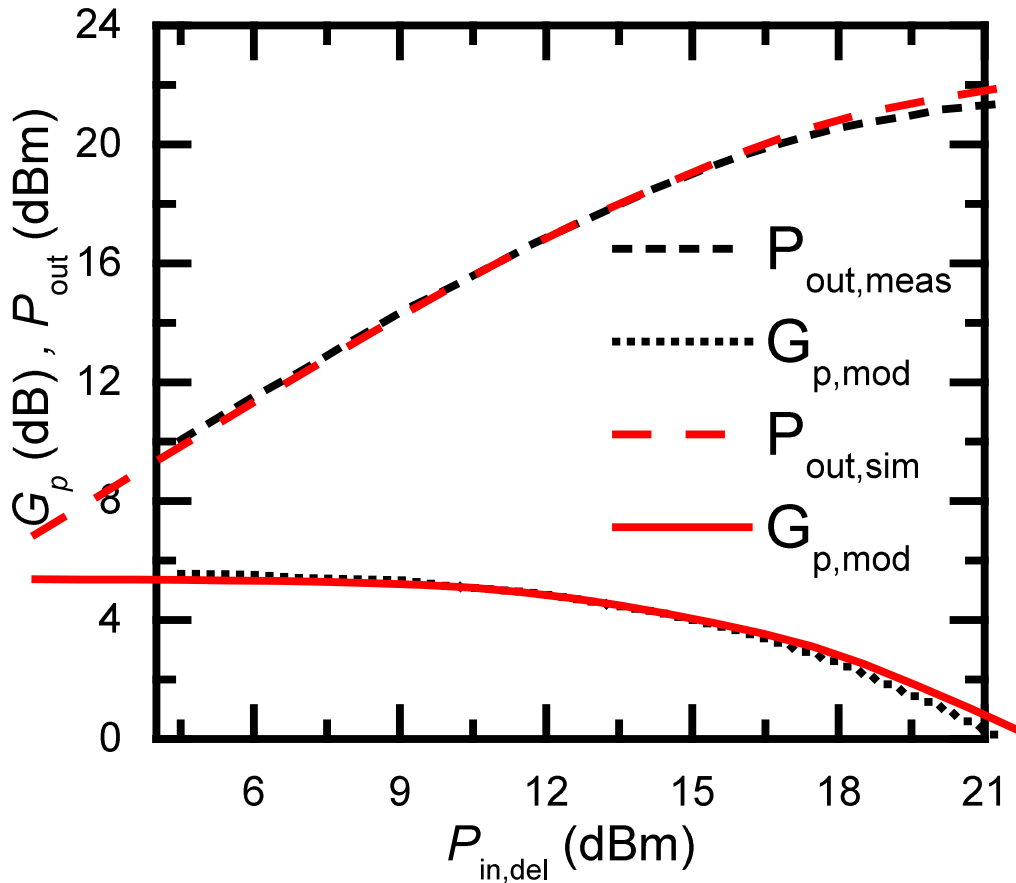
$d = 6 \text{ nm}$, $L_G = 100 \text{ nm}$, $L_{SD} = 1 \mu\text{m}$ on SiC.

No Back-Barrier. Regrown Contacts.



Best results at 94 GHz for AlInN-based HEMTs on SiC

PDK and PA Prototype Development (1)



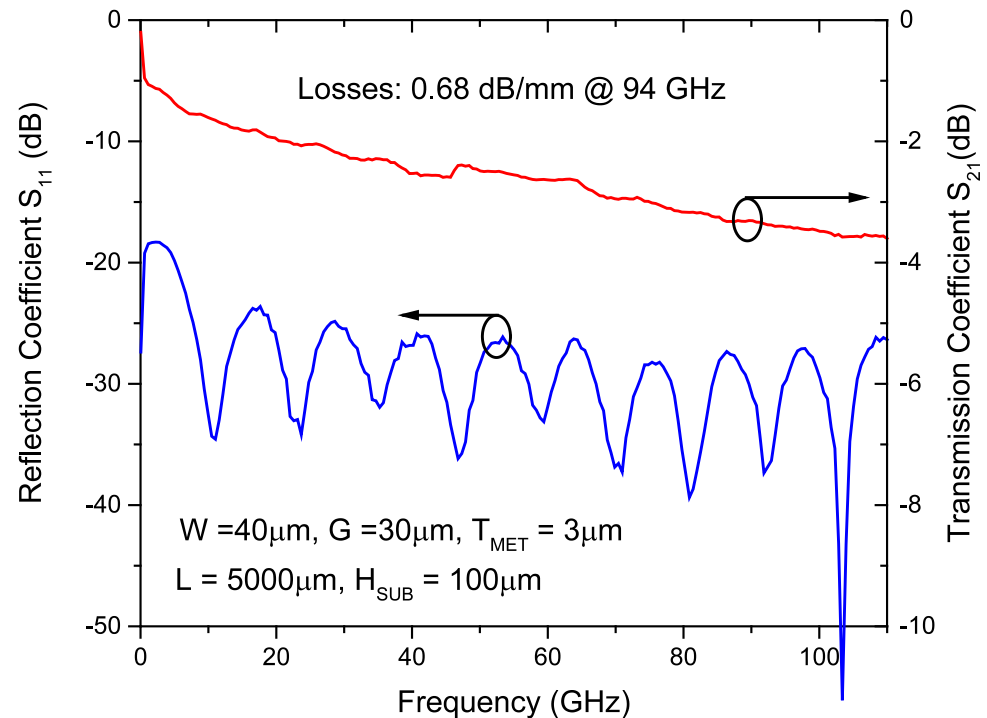
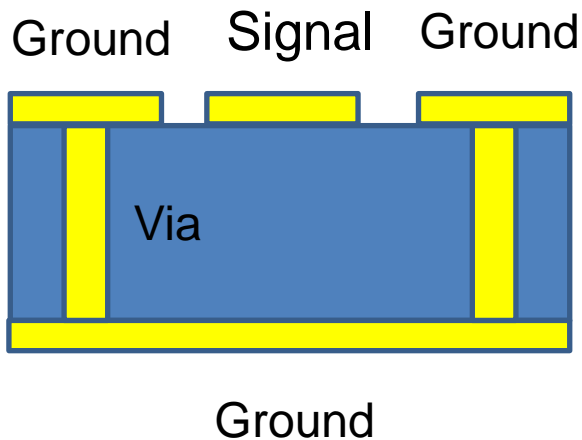
Large-Signal Model (Angelov)
Harmonic Balance Simulation
in ADS) vs. Load Pull
Measurement at 94 GHz for a
2x50um AlInN/GaN on Si
device.

Process Design Kit PDK

Scalable Large-Signal Model
(Gate Width & Fingers)

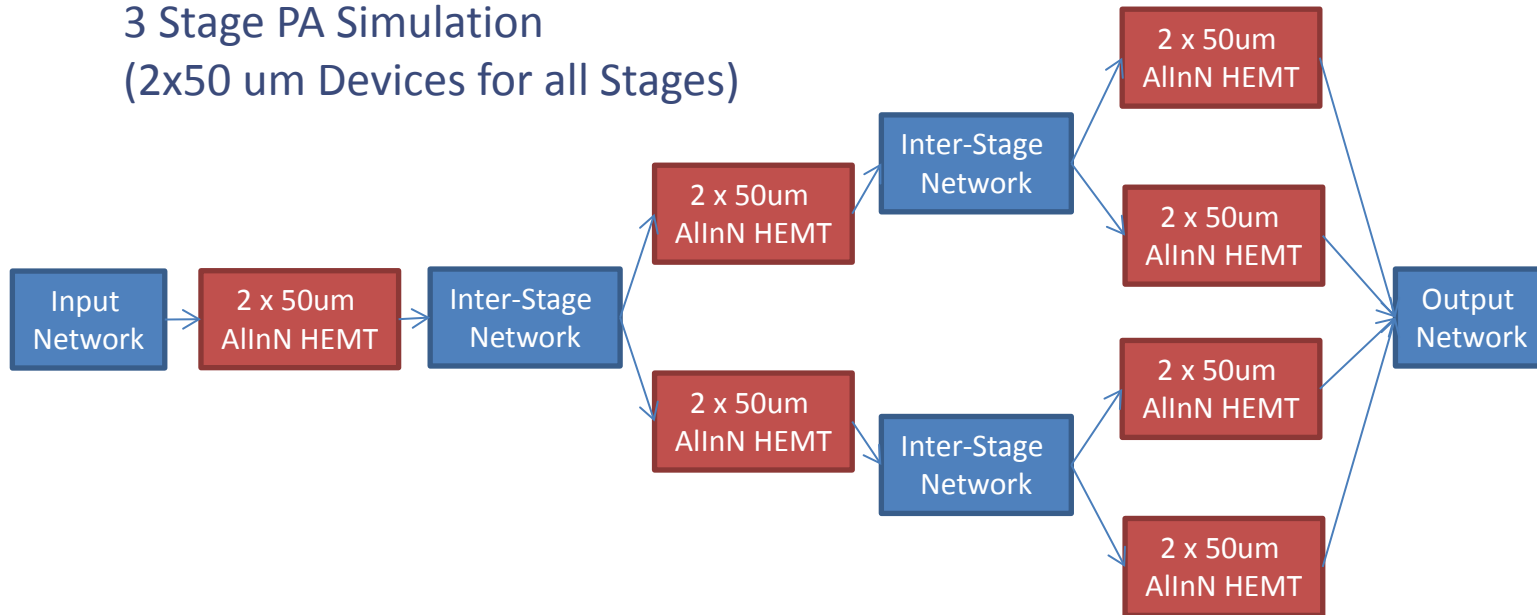
PDK and PA Prototype Development (2)

MMIC Process based on Grounded Coplanar Waveguides



PDK and PA Prototype Development (3)

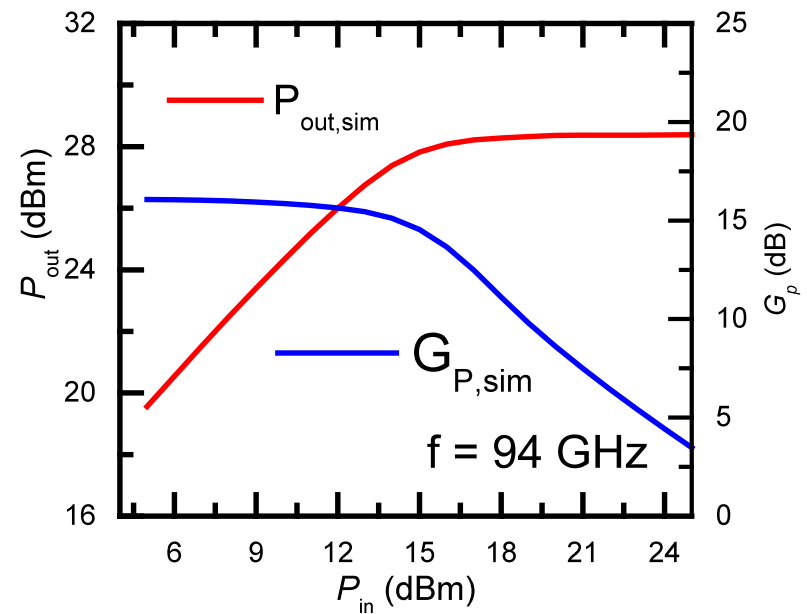
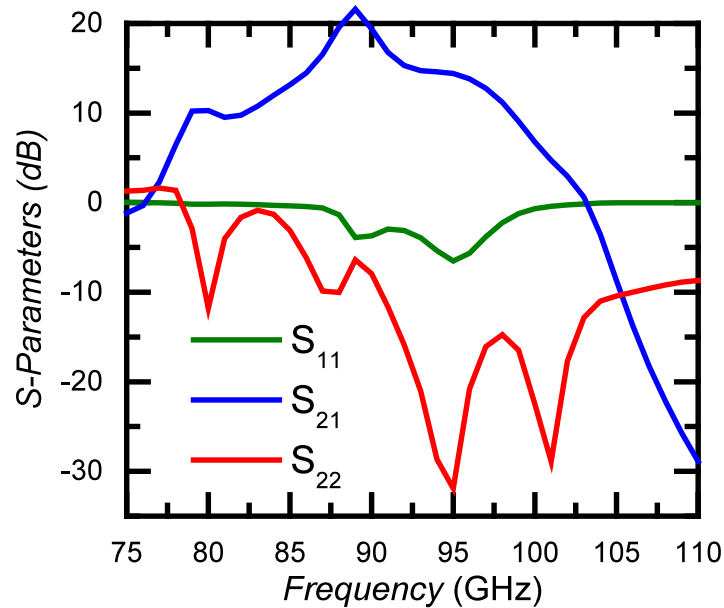
3 Stage PA Simulation
(2x50 um Devices for all Stages)



Input, Inter-Stage and Output Networks Simulated with Lumped Elements (Full Characterization and Modeling of Passives Elements are Underway)

PDK and PA Prototype Development (4)

- 3 Stage PA Simulation Results



- Additional Losses of 1 to 3 dB Expected with Lossy Interconnects in Implementation.

Conclusions

- **Excellent Progress with mm-Wave AlInN/GaN HEMTs**
 - Process Integration Developments (Back-Barrier / Regrown Ohmics)

- **GaN-on-Silicon is mm-Wave Ready**
- **Impressive P_{OUT} at 94 GHz on Silicon (1.3 W/mm)**
- **Improved Large-Signal Stability**

- **PDK and PA Prototype Development on Silicon**
 - W-Band Gain Block Feasible: 15 dB at W-Band
 - Refinements Required